



Attorney Docket No.: Q51885
PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Akitaka KIMURA

Appln. No.: 09/161,981

Confirmation No. Unknown

Group Art Unit: 2881

Filed: September 29, 1998

Examiner: J. Davie

For: SEMICONDUCTOR LAYER FORMED BY SELECTIVE DEPOSITION AND METHOD FOR
DEPOSITING SEMICONDUCTOR LAYER

RESPONSE UNDER 37 C.F.R. § 1.111

Commissioner for Patents
Washington, D.C. 20231

Sir:

In response to the Office Action dated March 28, 2001, Applicant traverses the Examiner's rejection of claims 1 - 4 and 9 - 17 based on the following remarks.

REMARKS

Claims 1-4 and 9-17 are all the claims pending in this application. Applicant confirms that claims 5-8 and 18-26 have been withdrawn from consideration.

Applicant notes that the Examiner has not acknowledged Applicant's claim to foreign priority under 35 U.S.C. § Section 119. Accordingly, Applicant respectfully requests that the Examiner acknowledge Applicant's claim to foreign priority in the next Office Action. Further, as discussed below, Applicant submits the verified English translation of the Japanese priority document.

Claims 1-4 and 9-17 stand rejected under 35 U.S.C. §103(a) as being unpatentable over Applicant's admitted prior art (APA) in combination with Hasegawa et al. (U.S. Patent No. 6,030,849). Given that Hasegawa is not prior art with respect to this application, Applicant respectfully traverses this rejection.

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